

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
1	BRS	L1	1	5771321.pn.	USPA T	2002/01/1 0 09:26	
2	BRS	L2	0	1 and (anisotropic and isotropic)	USPA T	2002/01/1 0 09:27	
3	BRS	L3	1	1 and (isotropic)	USPA T	2002/01/1 0 09:36	
4	BRS	L4	8	kamijima-\$.in.	US-P GPUB	2002/01/1 0 09:38	
5	BRS	L5	0	micromachine.ti.	US-P GPUB	2002/01/1 0 09:44	
6	BRS	L6	0	1 and pressure	US-P GPUB	2002/01/1 0 09:44	
7	BRS	L7	0	1 and ambient	US-P GPUB	2002/01/1 0 09:44	
8	BRS	L8	0	1 and air	US-P GPUB	2002/01/1 0 09:45	
9	BRS	L9	0	1 and (gas)	US-P GPUB	2002/01/1 0 09:45	
10	BRS	L10	0	1 and resin	US-P GPUB	2002/01/1 0 09:51	
11	BRS	L11	0	1 and vaccum	US-P GPUB	2002/01/1 0 09:52	
12	BRS	L12	0	1 and vacuum	US-P GPUB	2002/01/1 0 10:00	
13	BRS	L13	144	mold\$3 and photolithography and etching	US-P GPUB	2002/01/1 0 10:00	
14	BRS	L14	99	13 and micro\$	US-P GPUB	2002/01/1 0 10:07	
15	BRS	L15	1420	mold\$ and photolithography and etching	USPA T; US-P GPUB ; EPO; JPO; DERW ENT; IBM TDB	2002/01/1 0 10:09	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
16	BRS	L16	437	15 and micro\$	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2002/01/10 10:11	
17	BRS	L17	3	16 and (mold near1 transfer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2002/01/10 10:12	